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Braman et al.

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(54) **SYSTEMS AND METHODS FOR POTTED SHOCK ISOLATION**

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(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 457 days.

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(51) **Int. Cl.**
G01P 1/02 (2006.01)
G01C 21/16 (2006.01)

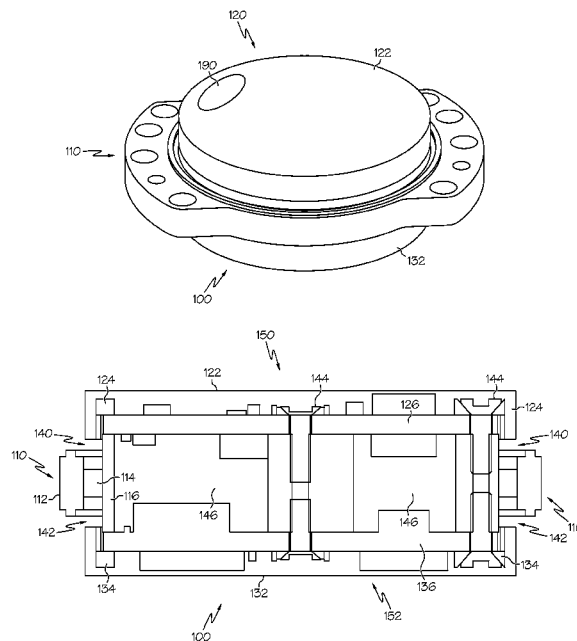
(52) **U.S. Cl.**
CPC **G01P 1/023** (2013.01); **G01C 21/16** (2013.01)

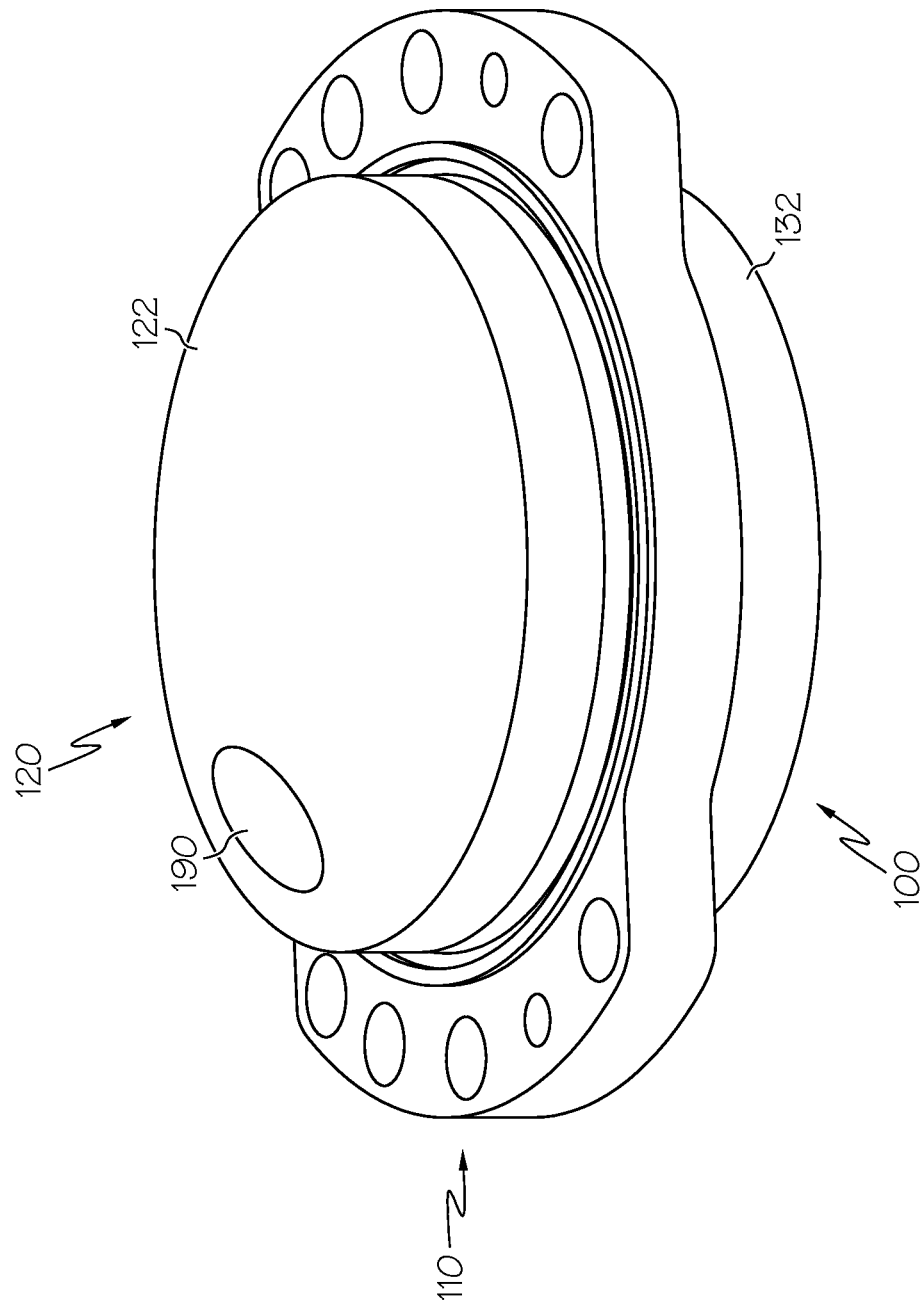
(58) **Field of Classification Search**
USPC 73/493
See application file for complete search history.

(57) **ABSTRACT**

Systems and methods for potted shock isolation are provided. In one embodiment a shock isolation system comprises an isolator comprising an outer ring for mounting to an external housing, and an inner ring connected to the outer ring via an isolating element; and an inertial sensing assembly comprising: at least one circuit board secured to the inner ring of the isolator, the at least one circuit board further comprising a triad of gyroscopes and a triad of accelerometers; and a low durometer highly dampened supporting material encapsulating a first surface of the at least one circuit board.

10 Claims, 7 Drawing Sheets





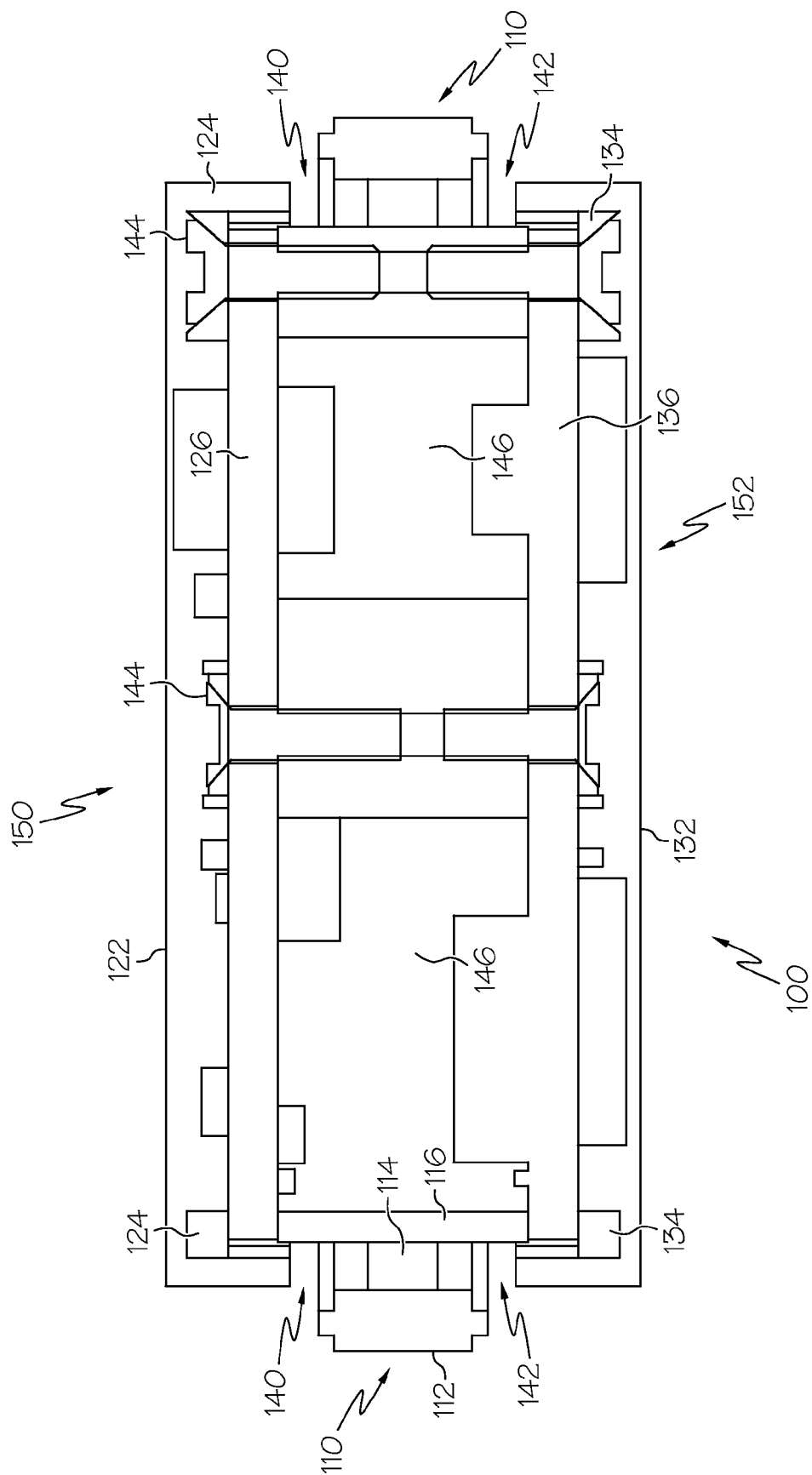


FIG. 1B

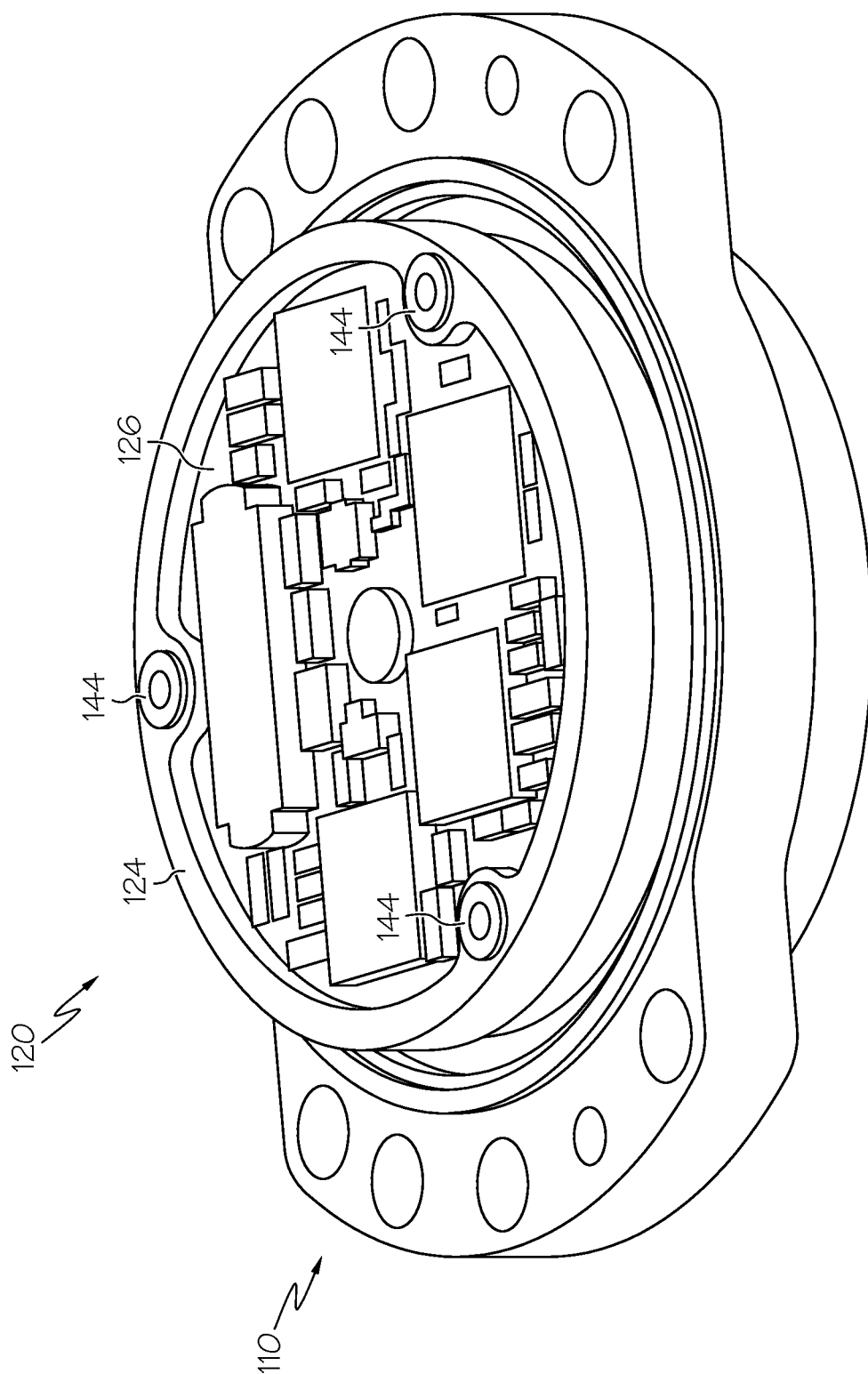


FIG. 1C

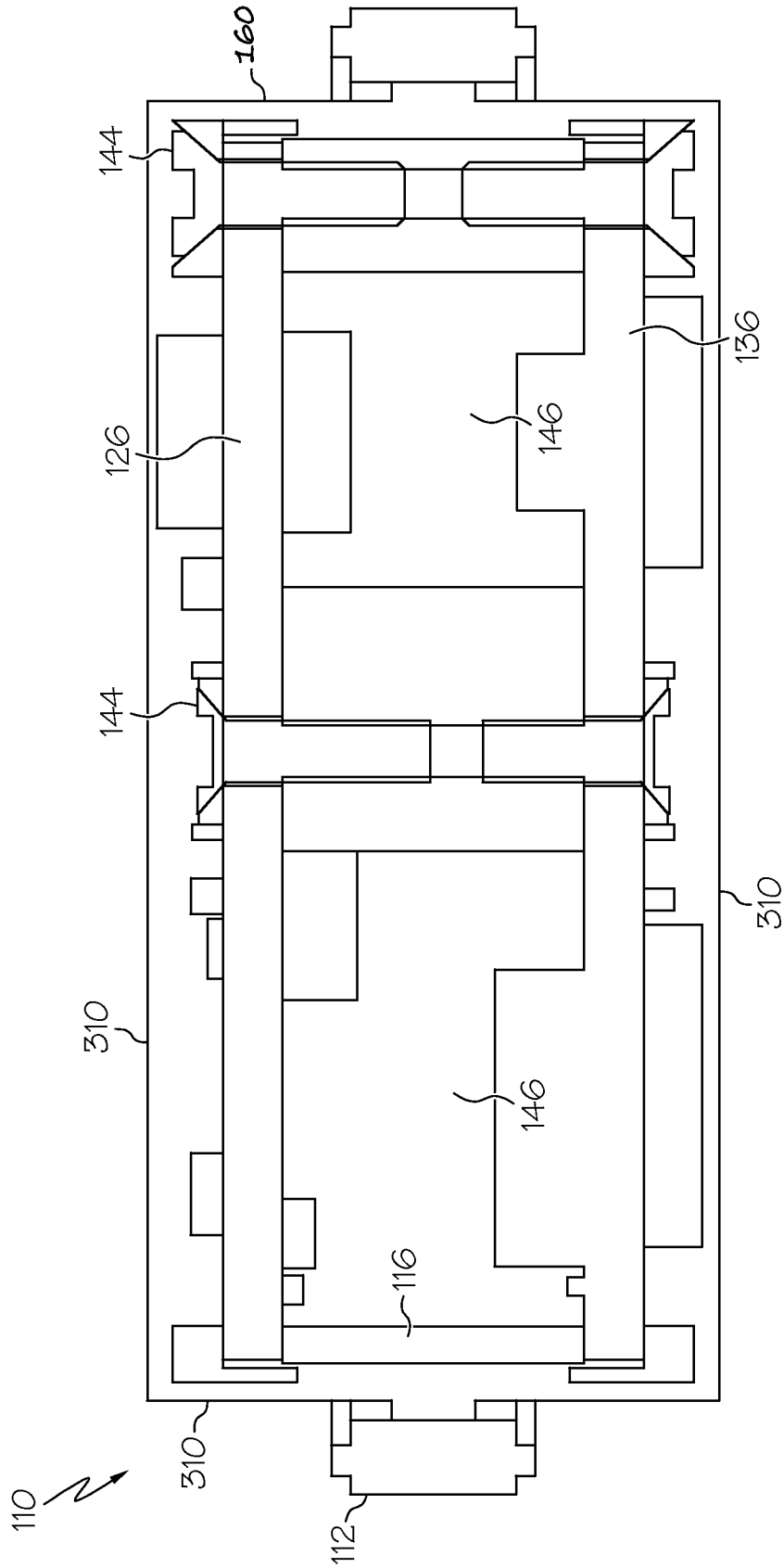


FIG. 1D

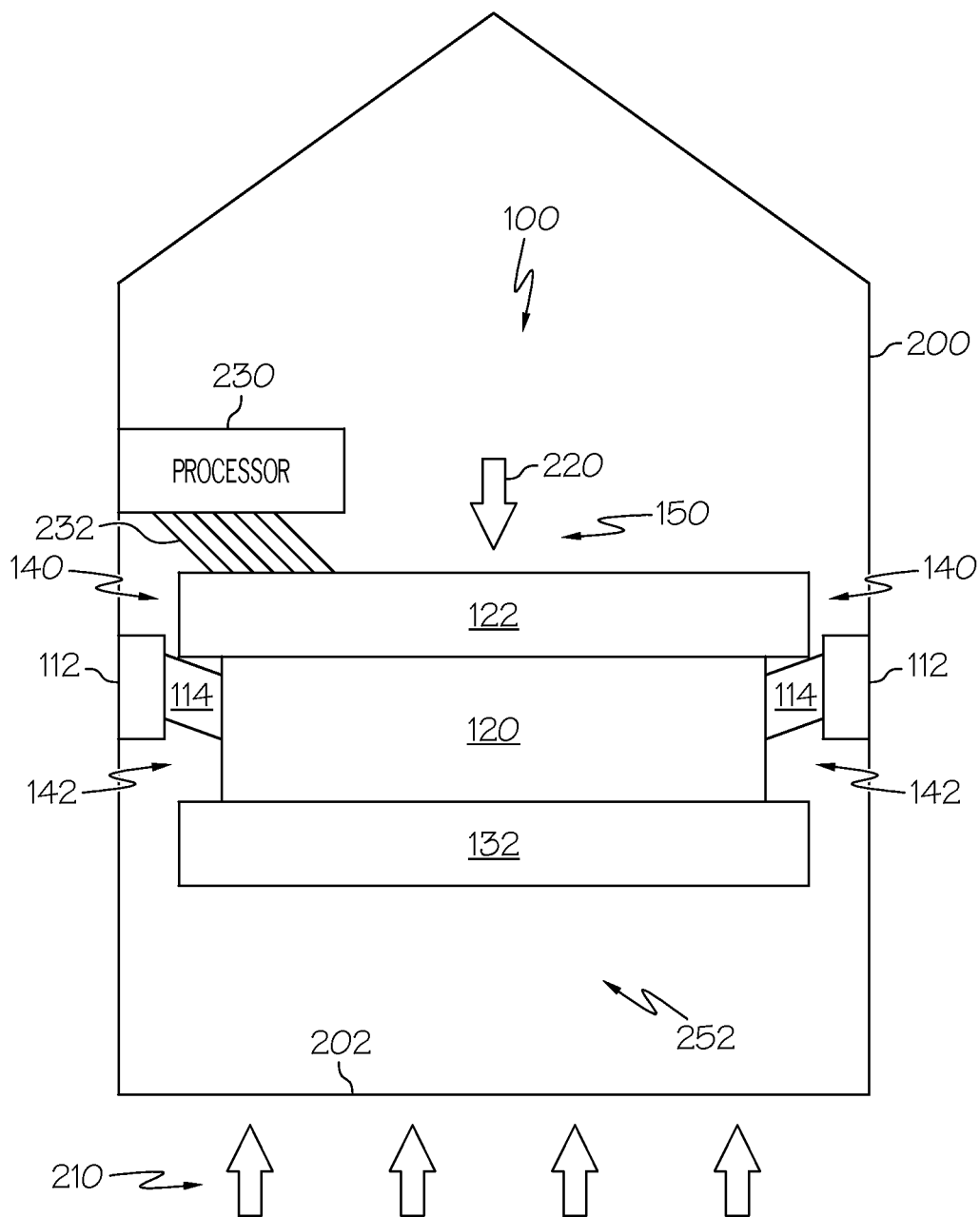


FIG. 2A

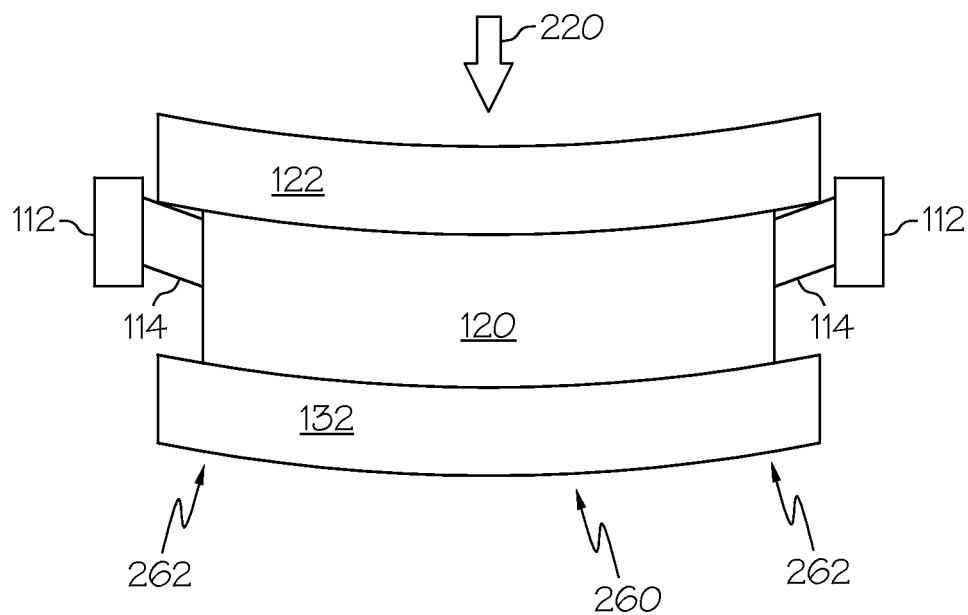


FIG. 2B

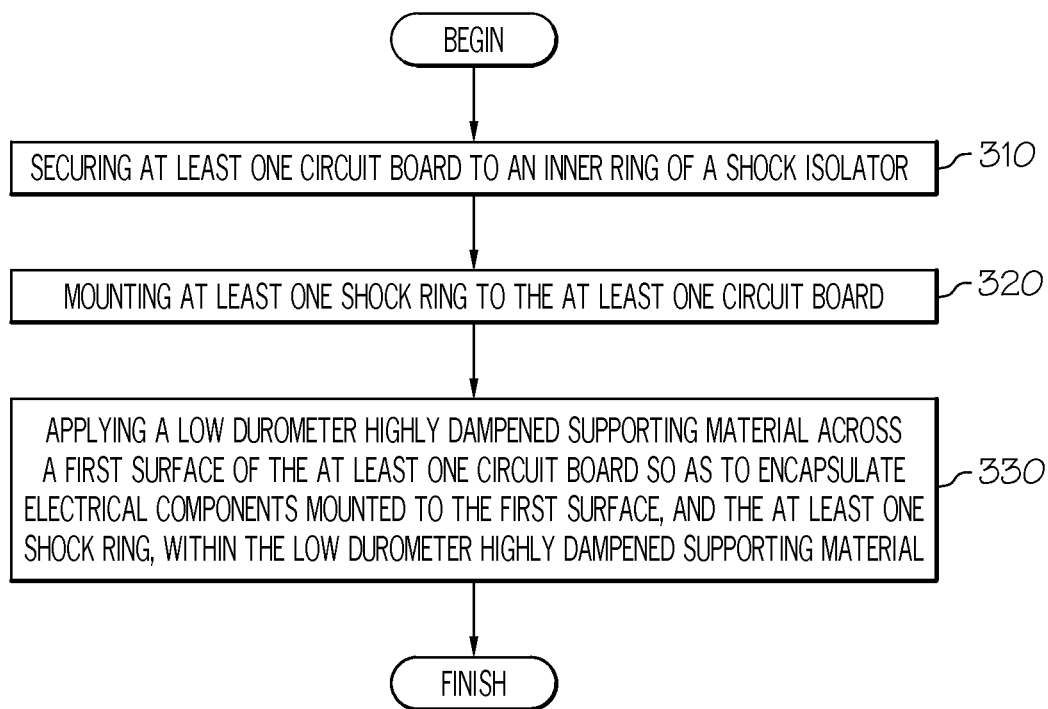


FIG. 3

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SYSTEMS AND METHODS FOR POTTED SHOCK ISOLATION

CROSS-REFERENCE TO RELATED APPLICATIONS

This application is a divisional of pending U.S. application Ser. No. 12/421,761 entitled "SYSTEMS AND METHODS FOR POTTED SHOCK ISOLATION," filed Apr. 10, 2009, which is incorporated herein by reference.

BACKGROUND

Inertial measurement units (IMUs) are used in a variety of applications such as air and space vehicles, watercraft vehicles, and guided missiles. IMUs detect the rate of acceleration and change in rotational attributes about three axes for a given time period. This data is used by a control system in order to track the application's position using a method known as dead reckoning. In one such application, Inertial Measurement Units (IMUs) are used to guide large caliber projectiles. During the launch of such a projectile, the IMU is subjected to high accelerations and thus requires ability to absorb this energy without incurring damage to the sensitive electronic components of which it is comprised. Current shock isolation systems for these applications include a rubber isolator for mounting the inertial sensing assembly (ISA), which is comprised of accelerometers and gyroscopes, within the IMU housing and a shock ring applied to the ISAs circuit board to absorb energy when it bottoms out during gun launch. Examples of such shock isolation systems are provided by U.S. Pat. No. 7,404,324, herein incorporated by reference. The problem with such current systems is that the shock ring still allows significant distortion of the ISAs circuit board due to bowing at the center of the board. Such bowing can damage the ISAs circuit board.

For the reasons stated above and for other reasons stated below which will become apparent to those skilled in the art upon reading and understanding the specification there is a need in the art for improved IMU shock isolation systems and methods.

SUMMARY

The Embodiments of the present invention provide methods and systems for an accelerated block option for TFTP file transfers and will be understood by reading and studying the following specification.

Systems and methods for potted shock isolation are provided. In one embodiment a shock isolation system comprises an isolator comprising an outer ring for mounting to an external housing, and an inner ring connected to the outer ring via an isolating element; and an inertial sensing assembly comprising: at least one circuit board secured to the inner ring of the isolator, the at least one circuit board further comprising a triad of gyroscopes and a triad of accelerometers; and a low durometer highly dampened supporting material encapsulating a first surface of the at least one circuit board.

DRAWINGS

Embodiments of the present invention can be more easily understood and further advantages and uses thereof more readily apparent, when considered in view of the description of the preferred embodiments and the following figures in which:

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FIGS. 1A-1D are illustration of a shock isolation system of one embodiment of the present invention;

FIGS. 2A and 2B are illustration of a shock isolation system within a projectile of one embodiment of the present invention;

FIG. 3 is a flow chart illustrating a method of one embodiment of the present invention.

In accordance with common practice, the various described features are not drawn to scale but are drawn to emphasize features relevant to the present invention. Reference characters denote like elements throughout figures and text.

DETAILED DESCRIPTION

In the following detailed description, reference is made to the accompanying drawings that form a part hereof, and in which is shown by way of specific illustrative embodiments in which the invention may be practiced. These embodiments are described in sufficient detail to enable those skilled in the art to practice the invention, and it is to be understood that other embodiments may be utilized and that logical, mechanical and electrical changes may be made without departing from the scope of the present invention. The following detailed description is, therefore, not to be taken in a limiting sense.

Embodiments of the present invention improve on the prior art by applying a low durometer highly dampened supporting material across outward facing surfaces of the ISA circuit board to encapsulate both the surface of the circuit board and shock ring within the material. Thus when the isolated ISA assembly bottoms out, the ISA circuit board is supported across its whole surface to reduce bowing of the ISA circuit board.

FIGS. 1A-1C illustrate a shock isolation system **100** of one embodiment of the present invention. FIG. 1A shows a shock isolation system **100** comprises an isolator **110** coupled to an isolated ISA **120** having a forward region supporting material **122** and a back region supporting material **132** molded across outward facing surfaces of the ISAs circuit boards.

FIG. 1B provides a cut-away view to illustrate shock isolation system **100** in greater detail. As shown in FIG. 1B, isolator **110** further comprises an outer ring **112** for securing shock isolation system **100** to an external housing and inner ring **116** for attaching ISA **120** which are connected via an isolating element such as isolating ring **114** (comprised of a silicon rubber, for example). ISA **120** comprises a first circuit board **126** and a second circuit board **136**. In one embodiment, one circuit board comprises a triad of accelerometers while the other circuit board comprises a triad of gyroscopes. The first circuit board **126** and second circuit board **136** are respectively mounted onto inner ring **116** of isolator **110**. The first circuit board **126** is mounted onto a forward region side **150** (the side facing the direction of launch) of the inner ring **116**. The second circuit board **136** is mounted onto a back region side **152** (the side facing away from the direction of launch) of the inner ring **116**.

In order to mitigate projectile launch shock forces, a shock ring **124** is mounted about the periphery of the first circuit board **126**. A supporting material **122** covers the forward region side **150** of the ISA **120** by encapsulating the outer surface of the first circuit board **126** and extending over the outer surface of first shock ring **124** while leaving an air gap **140** around the periphery of ISA **120** between supporting material **122**, isolating ring **114**, and the structure within which the ISA **120** is contained (as discussed below for FIG. 2A). Similarly, a shock ring **134** is also mounted about the

periphery of the second circuit board **136**. A supporting material **132** covers the back region side **152** of the ISA **120** by encapsulating the outer surface of the second circuit board **136** and extending over the outer surface of second shock ring **134** while leaving an air gap **142** around the circumference of IMU **120** between supporting material **132** and isolating ring **114**. For further illustration, FIG. 1C provides a view of shock isolation system **100** with supporting material **122** pulled away to reveal shock ring **124** and first circuit board **126**. As mentioned above supporting materials **122** and **132** are comprised of a low durometer highly dampened material such as a silicon rubber. One of ordinary skill in the art, upon reading this specification, would be able to readily select a material for implementing supporting materials **122** and **132** based on the volume and mass of the ISA and the surface area of the circuit boards and by further considering the particular frequency response and dampening requirements of the application.

Supporting material **132**, being in the set back region, will experience greater structural stresses during gun launch than the supporting material **122** in the set forward region. For this reason, in one embodiment supporting materials **132** on back region side **152** is thicker than supporting materials **122** on front region side **150**. In one embodiment, one or both of supporting materials **122** and **132** further include at least one connector penetration **190**. Connector penetration **190** may comprise a potted connector or similar device to provide an electrical signal and/or power interface between circuit boards **126** and **136** and at least one external device, such as a processor.

Although FIGS. 1A-1D illustrate, shock ring **124** mounted about the periphery of the first circuit board **126**, and shock ring **134** mounted about the periphery of the second circuit board **136**, alternate embodiments include shock isolation systems incorporating only one shock ring (mounted to one of the circuit boards) or shock isolation systems without a shock ring. In such embodiments, a circuit board without a shock ring may be mounted to the inner ring **116** of isolator **110** with fasteners or a glue (such as epoxy, for example) and the supporting material would be applied over exposed surfaces that contact the housing.

FIG. 2A is an illustration of an IMU **200** comprising a shock isolation system **100** for an ISA **120** of one embodiment of the present invention. IMU **200** further includes a processor **230** that is coupled to ISA **120** via a flexible cable **232** or similar connection. As shown, outer ring **112** of the isolator is secured within the body of IMU **200** which provides a housing for shock isolation system **100**. In one embodiment, outer ring **112** of the isolator is an integral part of the body or other structural component of IMU **200**. In operation during a launch, IMU **200** experiences an extreme acceleration (illustrated generally at **210**) in the direction of launch. This acceleration **210** generates counter inertial forces (shown generally at **220**) which act upon ISA **120**, causing a relative displacement of ISA **120** with respect to the body of projectile **200** towards a setback region **252**. The compliance of the isolating element **114** allows for such displacement until the bottom surface of **132** contacts the IMU **200** housing surface **202**. A similar deflection can occur in the opposite direction due to the deceleration of the projectile. As ISA **120** thus bottoms out, shock rings **124** and **134** support the periphery of circuit boards **126** and **136**, respectively depending on acceleration or deceleration, preventing further displacement of these portions of circuit boards **126** and **136**. However, as illustrated in FIG. 2B, although shock rings **124** and **134** support the periphery of circuit boards **126** and **136**, the counter inertial forces **220** continue to act on ISA **120**

causing it to bow at its center (shown generally at **260**). Encapsulation of the circuit boards **126** and **136** by the supporting materials **122** and **132** acts to provide additional support across the whole surface of the circuit boards to restrict this bowing to a level that will not damage the circuit board.

Referring back to FIG. 1B, in one alternate embodiment, the cavity **146** formed between the first circuit board **126**, the second circuit board **136** and the inner ring **116**, is also filled with a supporting material. The supporting material may be the low durometer highly dampened material used for supporting materials **122** and **132**, or alternatively may be another supporting material. The exact material used can be readily determined by one of ordinary skill in the art upon reading this specification. Filling cavity **146** with the supporting material provides even further protection from bowing by supporting both sides of the circuit boards. In one embodiment, the supporting material may further comprise carbon or a similar heat conductor, to absorb thermal energy generated by the electrical components of the circuit boards and transfer that heat to the environment surrounding ISA **120**. Although FIG. 1A illustrates application of supporting material **122** onto circuit board **126** resulting in a smooth surface, in alternate embodiments, the exposed surfaces of supporting materials **122** and **132** may be contoured or otherwise textured with bumps, dimples, divots, or other shapes. In yet another embodiment, illustrated by FIG. 1D, the forward region supporting material, back region supporting material and the isolating ring **114** of isolator **110** are integrated together encapsulating the whole of inner ring **116** and circuit boards **126** and **136** with a single supporting material unit **160**.

FIG. 3 is a flow chart illustrating a process for providing shock isolation for an inertial measurement unit of one embodiment of the present invention. The method begins at **310** with securing at least one circuit board to an inner ring of a shock isolator. In one embodiment, the at least one circuit board is mounted to the inner ring of the isolator with one or more fasteners. In one embodiment, a first circuit board is mounted to a forward region side of the shock isolator while a second circuit board is mounted to a back region side of the shock isolator. Circuit boards may include various electronic devices such as, but not limited to inertial sensor gyroscopes and accelerometers. In one embodiment, securing at least one circuit board to an inner ring comprises securing a triad of mutually orthogonally oriented gyroscopes and a triad of mutually orthogonally oriented accelerometers to the inner ring. The method proceeds to **320** with mounting at least one shock ring to the at least one circuit board. Mounting a shock ring to the circuit board structurally protects the circuit board from twisting motions and shock forces experienced during rapid acceleration conditions. The method proceeds to **330** with applying a low durometer highly dampened supporting material across a first surface of the at least one circuit board so as to encapsulate electrical components mounted to the first surface, and the at least one shock ring, within the low durometer highly dampened supporting material. The method may further comprise filling at least one cavity located within the inner ring of the shock isolator with the low durometer highly dampened supporting material.

In one embodiment, the low durometer highly dampened supporting material is a silicon rubber material. In one embodiment applying a low durometer highly dampened supporting material further comprises encapsulating the inner ring of the isolator within the low durometer highly dampened supporting material to form a single supporting material unit. In one alternate embodiment, the method further comprises providing at least one connector penetration within the low durometer highly dampened supporting material to pro-

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vide for an electrical signal and/or power interface between the at least one circuit board and an external device, such as a processor.

Although specific embodiments have been illustrated and described herein, it will be appreciated by those of ordinary skill in the art that any arrangement, which is calculated to achieve the same purpose, may be substituted for the specific embodiment shown. This application is intended to cover any adaptations or variations of the present invention. Therefore, it is manifestly intended that this invention be limited only by the claims and the equivalents thereof.

What is claimed is:

1. A method for providing a shock isolation for an inertial measurement unit, the method comprising:
 - securing at least one circuit board to an inner ring of a shock isolator, the at least one circuit board and shock isolator defining an inertial sensor assembly; and
 - applying a low durometer highly dampened supporting material across a first surface of the at least one circuit board so as to encapsulate electrical components mounted to the first surface within the low durometer highly dampened supporting material; wherein the low durometer highly dampened supporting material forms an external enclosure of the inertial sensor assembly, the low durometer highly dampened supporting material of the external enclosure further encapsulating and potting one or more electrical components mounted to the first surface within the low durometer highly dampened supporting material.
2. The method of claim 1, further comprising:
 - mounting at least one shock ring around a periphery of the at least one circuit board, wherein the low durometer highly dampened supporting material further encapsulates the at least one shock ring.

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3. The method of claim 1, further comprising:
 - mounting a first circuit board to a forward region side of the shock isolator; and
 - mounting a second circuit board to a back region side of the shock isolator.
4. The method of claim 1, wherein securing at least one circuit board to an inner ring of a shock isolator further comprises:
 - securing a triad of mutually orthogonally oriented gyroscopes and a triad of mutually orthogonally oriented accelerometers to the inner ring.
5. The method of claim 1, further comprising:
 - filling at least one cavity located within the inner ring of the shock isolator with a second supporting material.
6. The method of claim 1, wherein the low durometer highly dampened supporting material comprises a silicon rubber.
7. The method of claim 1, wherein the low durometer highly dampened supporting material comprises a carbon material.
8. The method of claim 1, wherein applying the low durometer highly dampened supporting material further comprises encapsulating the inner ring of the isolator, at least one shock ring, and the at least one circuit board within a supporting material unit.
9. The method of claim 1, further comprising:
 - providing at least one connector penetration within the low durometer highly dampened supporting material.
10. The method of claim 1, wherein an exposed surface of the low durometer highly dampened supporting material is contoured.

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